Electrostatic Chuck Controller

Features

- Provide two phase voltages of equal magnitude and opposite phase
- Provide the penetration voltage for wafer use
- Provide capacitance detection, for indicator of no-wafer, wafer-clamped, and release status
- Provide penetration detection, for indicator of penetration status
- LCD displayer, with the value of clamping and penetration voltage, resistance and capacitance detection

Description

The electrostatic chuck controller, which is a bipolar reversible power supply, specially designed for the application of electrostatic chuck for clamping Wafer in vacuum environment. Through the two high voltage connectors of the controller, 0~500V high voltage is injected into the electrostatic chuck with opposite polarity, and the release voltage with opposite polarity can also be provided. In addition, the controller can realize the function of penetrating the Wafer and provide 1000~4000V penetration voltage to the electrostatic chuck through the penetration voltage interface. At the same time, the controller can monitor the clamping/release status of Wafer as well as the result of the penetration.

The controller, with DB9 interface, which can communicate with the host computer, control the functions of the controller by sending commands from the host computer, and monitor the running status of the controller.

Technical Specifications

	Parameter
Input	100~264VAC/47~63Hz
Communication	RS-485 (RTU&ASCII)
Clamping voltage	0~±500V, ±2%FS
Penetration voltage	1000~4000V, ± 5%FS
Ambient	Operating:0°C~45°C;25~60%HR
	Storage:-35°C~85°C;25~60%HR
Dimensions	482.6mm×88.1mm×361.8mm(W×H×D)